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Contents

OPTM-1

11927 02 **Single pixel imaging and its applications (Invited Paper)** [11927-1]

11927 03 **Ghost imaging with probability estimation using convolutional neural network: improving estimation accuracy using parallel convolutional neural network** [11927-2]

11927 04 **Time of flight three-dimensional imaging camera using temporal compressive sampling technique** [11927-3]

11927 05 **On the possibility of visualization of relief of rough surfaces via laser induced thermal emission** [11927-4]

OPTM-2

11927 06 **Preparation of luminescent Si nanocrystals from rice husks (Invited Paper)** [11927-5]

11927 07 **Simulation study on diameter measurement technique for submicrometer-sized tapered fibers with standing wave illumination** [11927-6]

11927 08 **Shape control using hologram-assisted talbot lithography** [11927-7]

11927 09 **Hologram optimized in holographic laser processing system** [11927-8]

OPTM-3

11927 0A **3D profile measurement of openings with optical caliper (Invited Paper)** [11927-9]

11927 0B **Modeling the dynamic optical gain in a 3D printed waveguide due to polymer swelling** [11927-10]

11927 0C **Single-step fabrication of microfiber long period grating structure through a modulated arc discharge process** [11927-11]

OPTM-4

11927 0D **Noise floor comparison of optical displacement measuring interferometer between air and vacuum environments (Invited Paper)** [11927-12]

11927 0E Radius measurement of large aperture long-focal-length lens using computer-generated hologram [11927-13]

11927 0F Out-of-plane displacement measurement using laser parallel fringes generated in camera with diffraction grating [11927-14]

11927 0G Optically smooth and optically rough surfaces in 3D profilometry (Invited Paper) [11927-15]

OPTM-5

11927 0H Mid-infrared (LWIR) Hyperspectral camera for on-site analysis (Invited Paper) [11927-16]

11927 0I Fringe projection method for 3D shape measurement using linear LED device and cylindrical lens array [11927-17]

11927 0J The FDTD analysis for diffraction limited microgroove structure with standing wave illumination for the realization of coherent structured illumination microscopy [11927-18]

11927 0K Resolution evaluation of displacement measuring interferometer with sinusoidal phase modulation and modified phase-locked loop [11927-19]

OPTM-6

11927 0L Fourier demodulation approach for a rotating polarizer analyzer polarimeter for retardance measurements (Invited Paper) [11927-20]

11927 0M Large scale thin film thickness uniformity extraction based on dynamic spectroscopic ellipsometry [11927-21]

11927 0N Spectroscopic polarization measurement and control using channeled spectrum (Invited Paper) [11927-22]

OPTM-7

11927 0O Ellipsometric characterizations of individual nanoform structures [11927-23]

11927 0P Optical and anisotropic stress properties of flexible $(Ta_2O_5/SiO_2)^2$ antireflection film deposited by E-gun evaporation with ion-beam assisted deposition [11927-24]

POSTER SESSION

11927 0Q Calibration of the astigmatism errors induced by misalignment of quadri-wave lateral shearing interferometer [11927-25]

11927 0R **Quality map guided parallel phase unwrapping algorithm for multi-lateral shearing interferometry** [11927-26]

11927 0S **Fast calibration for Star test polarimetry via polarization orthogonal basis mapping** [11927-27]